

Notice of References Cited	Application/Control No. 10/585,845		Applicant(s)/Patent Under Reexamination MISAWA ET AL.	
	Examiner STEPHANIE DUCLAIR		Art Unit 4171	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
	E	US-			
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	G	US-			
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	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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	N	JP 2003236929 A	08-2003	Japan	URAIRI et al.	B29C 59/16
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)			
	U	Zhao et al, Fabrication of Microstructures Using Shrinkable Polystyrene Films, Sensors and Actuators, 1998, Edition 65, Pages 209-217			
	V	Misawa et al, Microfabrication by Femtosecond laser Irradiation, Laser Applications in Microelectronic and Optoelectronic Manufacturing V, 2000, Vol. 3933, Pages 246-260			
	W	JP 2003236929 Machine Translation			
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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